

Docket No.: 057810-0088

## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Customer Number: 20277

Eiji MARUYAMA

Confirmation Number: 2908

Application No.: 10/790,759

Group Art Unit: 1709

Filed: March 03, 2004

Examiner: Not Yet Assigned

For: PHOTOVOLTAIC DEVICE AND DEVICE HAVING TRANSPARENT CONDUCTIVE

**FILM** 

## INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection or Notice of Allowance.

10/790,759

**CERTIFICATION PARAGRAPH** 

The undersigned certifies that each item of information contained in this Information

Disclosure Statement was first cited in a communication from a foreign patent office in a

counterpart foreign application not more than three months prior to the filing of this Information

Disclosure Statement as described in 37 CFR 1.97(e)(1).

Each reference was cited in a corresponding foreign application search report and its

relevance is discussed therein. A copy of the foreign search report is attached for the Examiner's

information.

Please charge any shortage in fees due in connection with the filing of this paper,

including extension of time fees, to Deposit Account 500417 and please credit any excess fees to

such deposit account.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP

Please recognize our Customer No. 20277

as our correspondence address.

Stephen A. Becker

Registration No. 26,527

600 13<sup>th</sup> Street, N.W. Washington, DC 20005-3096

Phone: 202.756.8000 SAB:jwp

Facsimile: 202.756.8087

Date: May 10, 2007

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SHEET <u>1</u> OF <u>1</u>

INFO	CIT	ATION DISCLO CATION IN AN PPLICATION	ATTY. DOCKET NO. 057810-0088	SERIAL NO. 10/790,759						
			APPLICANT Eiji MARUYAMA							
	(	(PTO-1449)	FILING DATE March 03, 2004	March 03, 2004 1709						
		1	U.S. PATEN	NT DOCUMENTS						
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code2 (# known)	Publication Da MM-DD-YYY		Name of Patentee or Applicant of Cited Document			Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
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EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes -Number 4 -Kind Codes (if known)	Publication Dat MM-DD-YYYY			Columns, Lines re Relevant res Appear Yes No				
		EP 1 187 223 A2	03-13-2002	SANYO ELECTRIC CO., LTD			X			
		EP 0 892 590 A2	01-20-1999	TDK CORPORATION			Х			
		EP 0 461 908 A2	12-18-1991	FUJITSU LIMITED			Х			
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)  EXAMINER'S Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine,								<del> </del>		
INITIALS	CITE NO.	journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.								
		NEERINCK, D.G., et al., "Depth profiling of thin ITO films by grazing incidence X-ray diffraction", THIN SOLID FILMS, May 15, 1996, Pages 12-17, Elsevier Science S.A.								
	JOSHI, R.N., et al., "Characteristics of indium tin oxide films deposited by r.f. magnetron sputtering", THIN SOLID FILMS, February 15, 1995, Pages 32-35, Elsevier Science S.A.									
		THILAKAN, P., et al., "Oxidation dependent crystallization behaviour of IO and ITO thin films deposited by reactive thermal deposition technique", MATERIAL SCIENCE & ENGINEERING B, 1998, Pages 195-200, Elsevier Science S.A.								
		European Search Report issued in corresponding European Patent Application No. EP 04 25 1457, dated April 13, 2007								
EXAMINER					DATE CONSIDERED					
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<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.